## 10/562751 IAP20 Rec'd PCT/PTO 28 DEC 2005

**PATENT** 

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

## EXPRESS MAIL NO. <u>EV351242392US</u>

Appl No.

: \_N/A

Confirmation No.

**Applicant** 

: Akio Ishikawa

Filed

: December 28, 2005

Title

: PATTERN COMPARISON INSPECTION METHOD AND PATTERN

COMPARISON INSPECTION APPARATUS (AS AMENDED)

TC/A.U.

: N/A

Examiner

: N/A

Docket No.

: 56799/A400

Customer No. : 23363

## PRELIMINARY AMENDMENT

Commissioner for Patents

Post Office Box 7068

P.O. Box 1450

Pasadena, CA 91109-7068

Alexandria, VA 22313-1450

December 28, 2005

Commissioner:

Prior to examination, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.